We claim:

- 1. A gas sensor for determining the concentration of a gas component of a measurement gas, comprising:
- a layer structure including a reference electrode completely surrounded by a gastight material and;
 - a catalytically active working electrode which is to be exposed to the measurement gas.
- 2. The gas sensor of claim 1, wherein the gastight material is formed at least in sections by a solid electrolyte to which both the reference electrode and the working electrode are connected.
- 3. The gas sensor of claim 2, wherein the solid electrolyte is formed by an oxide ion-conducting material.
- . 4. The gas sensor of claim 3, wherein the oxide ion-conducting material is yttrium-stabilized zirconium dioxide.
- 5. The gas sensor of claim 1, wherein the gastight material is formed in sections by a low-sodium glass cover layer.
- 6. The gas sensor of claim 1, wherein the gastight material is formed in sections by an electrically insulating carrier material.
 - 7. The gas sensor of claim 1, further including a heating system.
- 8. The gas sensor of claim 1, wherein the reference electrode has at least one material component which is chosen from the following group: metals, metal oxides, and mixtures thereof.

- 9. The gas sensor of claim 1, wherein the working electrode has at least one material component which is chosen from the following group: precious metals, precious metal alloys, oxides, oxide mixtures and mixtures thereof.
- 10. The gas sensor of claim 1, wherein the gas sensor operates according to a potentiometric measurement principle.
- 11. The gas sensor of claim 9, wherein the gas sensor is capable of measuring λ values which are below 0.9.
- 12. The gas sensor of claim 11, wherein the gas sensor is capable of measuring λ values below 0.6.
- 13. The gas sensor of claim 12, wherein the gas sensor is capable of measuring λ values below 0.4.
- 14. A process for producing a gas sensor used for determining the concentration of a gas component of a measurement gas, comprising the steps of:

providing a carrier layer of electrically insulating material; applying a solid electrolyte layer to the carrier layer; forming a reference electrode and a working electrode on the solid electrolyte layer; and

covering the reference electrode with a gastight cover layer.

15. A process for producing a gas sensor used for determining the concentration of a gas component of a measurement gas, comprising the following steps:

providing a carrier layer of electrically insulating material; forming a reference electrode on the carrier layer; covering the reference electrode with a gastight solid electrolyte layer; and forming a working electrode on the gastight solid electrolyte layer.

- 16. The process of claim 14, wherein electrically conductive connections are formed to the reference electrode and the working electrode.
- 17. The process of claim 14, wherein the solid electrolyte layer is formed by an oxide ion-conducting material.
- 18. The process as claimed in claim 14, wherein the cover layer is a low-sodium glass layer.
- 19. The process of claim 14, further comprising the step of forming an electrical heating system on a side of the carrier layer facing away from the reference electrode and the working electrode.
- 20. The process of claim 15, wherein the reference electrode has at least one material component chosen from the following group: metals, metal oxides, and mixtures thereof.
- 21. The process of claim 15, wherein the working electrode has at least one material component chosen from the following group: precious metals, precious metal alloys, oxides, oxide mixtures and mixtures thereof.
- 22. The process of claim 14, further comprising the step of choosing a catalytic activity of the working electrode such that the gas sensor is capable of measuring λ values which are below 0.9.
- 23. The process of claim 22, wherein the gas sensor is capable of measuring λ values below 0.6.
- 24. The process of claim 23, wherein the gas sensor is capable of measuring λ values below 0.4.